



Hitachi CG-4000

Serial Number:

Process Type: Metrology & Inspection

Wafer Size: 300mm

Date of Manufacture:

Equipment Information:

(Load Port C need repair)

Configuration:

Hitachi CG-4000; 3LP

Software V31

Options:

Signal Light Tower(with buzzer)

UL Safety Modification (S2-0200)

Circulator Input Voltage Modification

Automatic Beam Alignment on wafer

Optical magnification (x100 & x200)

AC208V input modification

Cable (15m) (for main unit thru power supply unit) SE-Gun back-up power supply unit

Ion pump back-up power supply unit

SPM (pre-focus only)

Multi-point Measurement

Gap meas

Corner radius meas

Image Filing Function

Output function to DOS format FD

Recipe queue

ArF package (multi)

Image info additional function to MSR file

Waveform matching

Large

pixel $A \times B$

Image enhancement

Mag. Max $\times 400k$

Dry Pump I/F "F" (for IL70)

GEM300

DS/T-PC link connection

license 100nm Microscale

Grounded Arm

FFU hood